課題番号 :F-15-NM-0100

利用形態 :技術代行

利用課題名(日本語) :パリレン HT ライナーのスルーシリコンビアの検査

Program Title (English) :Inspection of a Through-Si-Via with Parylene-HT Liner

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1. 概要 <u>(Summary)</u>

Three-dimensional stacking technology has been developed for high-integration, high-speed and high performance electric devices. The through silicon via (TSV) approach realizes 3D integration by heterogeneous integration of multiple tiers of active components in vertically direct. In this research, a high-aspect ratio (AR) parylene-HT liner TSV for low-temperature compatible 3D integration will be inspected by FIB milling to confirm the formation of the TSV structure (Fig.1).

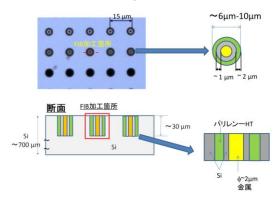


Fig1. Form TSVs and expected cross-section view.

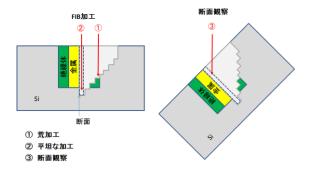


Fig. 2. FIB milling and observation procedure.

2. 実験 (Experimental)

【利用した主な装置】FIB-SEM Dual Beam System 【実験方法】High-aspect ratio (AR) parylene-HT liner TSVs were fabricated through Si etching, parylene liner deposition, and metal filling processes. The sample after that was FIB milled and inspected by a FIB-SEM double beam system (XVision200DB, Hitachi, Ltd.,) to confirm the formation of bumps. The experimental procedure is illustrated in Fig. 2.

3. 結果と考察(Results and Discussion)

The observation results are shown in Fig. 3. Since SEM is also equipped, real-time imaging at high resolution of a specimen is permitted during the FIB milling process. As a result, high-precision processing was implemented and the formation of bumps was confirmed.

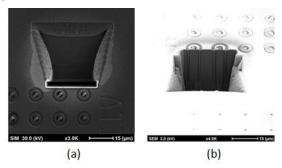


Fig. 3 TSV structure confirmed by FIB milling. (a), (b) are the top- and bird's eye-view of bump position after FIB milling process, respectively.

<u>4. その他・特記事項(Others)</u>

なし

5. 論文·学会発表(Publication/Presentation)

- (1) B. T. Tung, et.al, IEEE Transactions on Components, Packaging and Manufacturing Technology, 2016 (Accepted).
- (2) B. T. Tung, et.al, International conference on 3D Systems Integration Conference (3DIC), 2015, pp. 160–163.

6. 関連特許 (Patent)

なし